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CONFIRMATION NO. 2631

Bib Data Sheet

<b>SERIAL NUMBER</b> 10/027,935	<b>FILING OR 371(c) DATE</b> 12/21/2001 <b>RULE</b>	<b>CLASS</b> 451	<b>GROUP ART UNIT</b> 3724	<b>ATTORNEY DOCKET NO.</b> A-68359-1/RMA
<b>APPLICANTS</b> Gerard S. Moloney, Milpitas, CA; Jason Price, Eugene, OR; Scott Chin, Palo Alto, CA; Jiro Kajiwara, Cupertino, CA; Malek Charif, San Jose, CA;				
<b>** CONTINUING DATA *****</b> This application is a DIV of 09/390,142 09/03/1999 PAT 6,368,189 which is a CON of 09/294,547 04/19/1999 PAT 6,309,290 which is a CIP of 09/261,112 03/03/1999 PAT 6,231,428				
<b>** FOREIGN APPLICATIONS *****</b>				
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 01/31/2002</b>				
Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Allowance Verified and Acknowledged _____ Examiner's Signature Initials		<b>STATE OR COUNTRY</b> CA	<b>SHEETS DRAWING</b> 24	<b>TOTAL CLAIMS</b> 18
<b>INDEPENDENT CLAIMS</b> 6				
<b>ADDRESS</b> 32940				
<b>TITLE</b> Apparatus and method for chemical-mechanical polishing (CMP) head having direct pneumatic wafer polishing pressure				
<b>FILING FEE RECEIVED</b> 1666	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	